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ABSTRACT OF THE DISCLOSURE (FIG. 6)

"SUBSTRATE TREATMENT APPARATUS"

A substrate treatment apparatus comprises an arm holder for substantially horizontally holding each of substrates, a substrate transfer mechanism, having a vertical shaft, for moving the arm holder along the vertical shaft, swinging the arm holder about the vertical shaft, and horizontally advancing and retreating the arm holder, a first liquid process unit including a casing, a substrate carry-in/carry-out port formed in the casing and permitting a first substrate to be carried therethrough together with the arm holder, and a plurality of treatment members contained in the casing for treating the first substrate with a liquid, and a second liquid process unit located adjacent to the first liquid process unit, and including the casing, a substrate carry-in/carry-out port formed in the casing and permitting a first substrate to be carried therethrough together with the arm holder, and a plurality of treatment members contained in the casing for treating the second substrate with a liquid. Each of the treatment members of the first liquid process unit and a corresponding one of the treatment members of the second liquid process unit are arranged symmetrical on a horizontal plane with respect to the arm holder.

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